



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Shoriki NARITA et al.

Serial No. 10/019,700

Filed January 2, 2002

BUMP FORMING APPARATUS FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVAL METHOD
FOR CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVING UNIT FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, AND CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE

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: Examiner Igwe U. Anya]

THE COMMISSIONER IS AUTHORIZED
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ACCOUNT NO. 23-0975

SUBMISSION OF REFERENCES

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Applicants request that the references listed below be placed in the file of the above-identified application:

USP 6,198,616, 03/2001, Dahimene et al.
JP 01077111, 03/1989 (Abstract)
JP 2002009569, 01/2001 (Abstract)
JP 2002203995, 07/2002 (Abstract)

Respectfully submitted,

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